FORM PTO-1449 (REV.7-80)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. 856063.547D1			APPLICATION NO.			
INE	DM.	ATION DISCLOSU	APPLICANTS Salvatore Lombardo et al.								
Ш	JKIVI.	(Use several sheets if necessary)			FILING DATE July 7, 2003			P ART UNIT			
U.S. PATENT DOCUMENTS											
*EXAMINER DOCUMENT NUMBER DATE			· · · · · ·	NAME		CLASS SU		SUBCLASS	FILING DATE IF APPROPRIATE		
4.5-	AA	4,343,080	08/10/82	Hataishi et al.		29		571	/		
1	AB	5,028,557	07/02/91	Tsai et al.		437		59 ⁻			
	AC	5,126,278	06/30/92	Kodaira		437		24			
	AD	5,635,423	06/03/97	Huang et al.		437		195			
	ΑE	5,659,201	08/19/97	Wolleson		257		758			
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	AG	5,753,967	05/19/98	Lin				635			
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X-51	AL	03-292740	12/24/91	Japan							
1.5	AM	0697716A2	02/21/96	EP							
	AN										
OTHER PRIOR ART (Including Author, Title, Date, Pertinent Pages, Etc.)											
A.	AO	S. Wolf et al	S. Wolf et al., "Silicon Processing for the VLSI Era V1" - Process Technology, 1986, pp								
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		Engineers, No. 1988, pp 744-747, 1988.									
1	AQ	Lombardo, S. et al., "Ge Ion Implantation in Si for the Fabrication of Si/Ge Si Heterojunction Transistors," <i>Materials Chemistry and Physics</i> , 46(2-3), pp. 156-160, 1996.									
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* EXAMINER: Initial if reference considered, whether or not criteria is in conformance with MPEP 609. Draw line through citation if not in											
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